

Amendments to the Claims:

This listing of claims replaces all prior versions, and listings, of the claims in the applications.

Listing of Claims

Claim 1 -4 (Cancelled)

Claim 5 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

a silicon layer comprising substantially silicon for conducting light, and

a germanium layer comprising substantially germanium for conducting light; and

a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and

a second plurality of conductive contacts coupled to said silicon layer,

wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

where the diode structure is capable of producing and separating electron hole pairs

caused by photons absorbed in the depletion region,

wherein the cladding further comprises: a bottom cladding, a side cladding and a top cladding,

where each of the claddings is comprised of [[a]] the plurality of dielectric materials,

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive

contacts is operatively coupled to the CMOS transistor.

Claim 6 (original): The waveguide photodetector of claim 5, wherein one of the plurality of

dielectric materials comprising a layer of side cladding is formed from the same film as a dielectric component of a transistor, where the dielectric component is selected from a group comprising: an inter-layer dielectric film, a gate spacer, a silicide block, a dielectric spacer, a passivation film, an isolation dielectric and a field oxide.

Claim 7 (original): The waveguide photodetector of claim 5, wherein one of the plurality of dielectric materials comprising a layer of top cladding is formed from the same film as a dielectric component of a transistor, where the dielectric component is selected from a group comprising: an inter-layer dielectric film, a gate spacer, a silicide block, a dielectric spacer and a passivation film.

Claim 8 (original): The waveguide photodetector of claim 5, wherein the bottom cladding is comprised of the insulating layer of a substrate, where the substrate is selected from the group comprising: silicon on insulator (SOI), silicon on sapphire (SOS) and a silicon membrane (also known as silicon on nothing, SON).

Claim 9 (original): The waveguide photodetector of claim 5, further comprising the fabrication of the insulator of a SOI substrate of an integrated circuit at the same time as the fabrication of the bottom cladding of the waveguide.

Claim 10 (original): The waveguide photodetector of claim 9, wherein the integrated circuit is selected from the group comprising: a CMOS integrated circuit, a BiCMOS integrated circuit and a bipolar junction integrated circuit.

Claim 11 (Cancelled): The waveguide photodetector of claim 1, wherein at least one of the plurality of dielectric materials is selected from the group comprising: SiO₂, SiCOH, SiCOF, Si₃N₄, SiON, BPSG and silicon-based materials including one or more of the following elements: oxygen, carbon, nitrogen, hydrogen, boron, phosphorus, fluorine and arsenic.

Claim 12 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction stack comprising:

 a silicon layer comprising substantially silicon for conducting light, and

 a germanium layer comprising substantially germanium for conducting light; and

 a cladding comprised of a plurality of dielectric materials,

 a first plurality of conductive contacts coupled to said germanium layer, and

 a second plurality of conductive contacts coupled to said silicon layer,

 wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

 where the diode structure is capable of producing and separating electron hole pairs

 caused by photons absorbed in the depletion region,

 wherein each of the second plurality of conductive contacts comprises:

 an ohmic contact to the silicon of the heterojunction, and

 a conductive plug with a first terminal coupled to the ohmic contact and a second terminal

 coupled to a metal layer of an integrated circuit,

 wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

 are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive contacts is operatively coupled to the CMOS transistor.

Claim 13 (original): The waveguide photodetector of claim 12, wherein the conductive plug is formed simultaneously with the metal layer.

Claim 14 (original): The waveguide photodetector of claim 12, further comprising the fabrication of an ohmic contact on a terminal region of a transistor at the same time as the fabrication of an ohmic contact on the silicon of the heterojunction, where the terminal region of a transistor is selected from a group comprising: a source, a drain, a gate and a body.

Claim 15 (original): The waveguide photodetector of claim 12, further comprising the fabrication of a conductive plug to an ohmic contact of a transistor at the same time as the fabrication of a conductive plug to an ohmic contact to the silicon of the heterojunction.

Claim 16 (original): The waveguide photodetector of claim 12, wherein an ohmic contact is comprised of a metal silicide.

Claim 17 (original): The waveguide photodetector of claim 12, wherein a conductive plug is comprised of tungsten.

Claim 18 (original): The waveguide photodetector of claim 12, further comprising fabrication of a local interconnection between a pair of transistors, at the same time as fabricating a local

interconnection for coupling an ohmic contact on the silicon of the heterojunction with an ohmic contact on a transistor.

Claim 19 (original): The waveguide photodetector of claim 18, wherein the local interconnection is comprised of a material selected from the group comprising: tungsten and aluminum.

Claim 20 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

a silicon layer comprising substantially silicon for conducting light, and

a germanium layer comprising substantially germanium for conducting light; and

a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and

a second plurality of conductive contacts coupled to said silicon layer,

wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

where the diode structure is capable of producing and separating electron hole pairs

caused by photons absorbed in the depletion region,

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

are formed from a starting silicon layer, and

wherein at least one contact of the first and the second pluralities of contacts is coupled to a

metal layer on [[an]] the integrated circuit, where the metal layer has a coupling to an

element on the integrated circuit and where the element is selected from the group

comprising: a capacitor, a resistor, an inductor, a diode, a transistor and a bond pad.

Claim 21 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction stack comprising:

 a silicon layer comprising substantially silicon for conducting light, and

 a germanium layer comprising substantially germanium for conducting light; and

 a cladding comprised of a plurality of dielectric materials,

 a first plurality of conductive contacts coupled to said germanium layer, and

 a second plurality of conductive contacts coupled to said silicon layer,

 wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

 where the diode structure is capable of producing and separating electron hole pairs

 caused by photons absorbed in the depletion region,

 wherein each of the first plurality of conductive contacts comprises:

 an ohmic contact to the germanium of the heterojunction, and

 a conductive plug with a first terminal coupled to the ohmic contact and a second terminal

 coupled to a metal layer of an integrated circuit,

 wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

 are formed from a starting silicon layer, and

 wherein at least one conductive contact of the first and the second pluralities of conductive

 contacts is operatively coupled to the CMOS transistor.

Claim 22 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

a silicon layer comprising substantially silicon for conducting light, and

a germanium layer comprising substantially germanium for conducting light; and

a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and

a second plurality of conductive contacts coupled to said silicon layer,

wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

where the diode structure is capable of producing and separating electron hole pairs

caused by photons absorbed in the depletion region, ~~further comprising the introduction~~

~~of wherein~~ a plurality of dopants are introduced into a plurality of regions in the silicon of
the heterojunction,

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide
are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 23 (original): The waveguide photodetector of claim 22, further comprising the introduction of a plurality of dopants into a plurality of regions in the silicon body of a transistor at the same time as the introduction of the plurality of dopants into a plurality of regions in the silicon of the heterojunction.

Claim 24 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

a silicon layer comprising substantially silicon for conducting light, and

a germanium layer comprising substantially germanium for conducting light; and

a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and

a second plurality of conductive contacts coupled to said silicon layer,

wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,
where the diode structure is capable of producing and separating electron hole pairs
caused by photons absorbed in the depletion region, ~~further comprising the introduction
of wherein a plurality of dopants are introduced into a plurality of regions in the
germanium of the heterojunction,~~

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide
are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 25 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

a silicon layer comprising substantially silicon for conducting light, and

a germanium layer comprising substantially germanium for conducting light; and

a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and
a second plurality of conductive contacts coupled to said silicon layer,
wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,
where the diode structure is capable of producing and separating electron hole pairs
caused by photons absorbed in the depletion region, ~~further comprising the introduction~~
~~of wherein~~ a first plurality of dopants are introduced into a plurality of regions in the
silicon of the heterojunction, and ~~the introduction of~~ a second plurality of dopants are
introduced into a plurality of regions in the germanium of the heterojunction,
wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide
are formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 26 (original): The waveguide photodetector of claim 25, wherein the first plurality of dopants is comprised of dopants with electrical charge opposite to the polarity of the dopants comprising the second plurality of dopants.

Claim 27 (original): The waveguide photodetector of claim 25, wherein the first plurality of dopants is comprised of dopants with electrical charge equal to the polarity of the dopants comprising the second plurality of dopants.

Claim 28 (Currently Amended): A waveguide photodetector comprising:
a waveguide and an input to the waveguide photodetector, the waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:

- a silicon layer comprising substantially silicon for conducting light, and
- a germanium layer comprising substantially germanium for conducting light; and
- a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to said germanium layer, and

a second plurality of conductive contacts coupled to said silicon layer,

wherein the germanium on silicon heterojunction forms a diode structure with a depletion region,

where the diode structure is capable of producing and separating electron hole pairs caused by photons absorbed in the depletion region, ~~further comprising an input to the waveguide photodetector~~

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive contacts is operatively coupled to the CMOS transistor.

Claim 29 (original): The waveguide photodetector of claim 28, further comprising a silicon waveguide with an input and an output, where the output of the silicon waveguide is coupled to the input of the waveguide photodetector.

Claim 30 (previously presented): The waveguide photodetector of claim 28, further comprising:

- a silicon waveguide with an input and an output; and,
- a mode converter with an input and an output, where the output of the mode converter is coupled

to the input of the waveguide photodetector, and where the input to the mode converter is coupled to the output of the silicon waveguide.

Claim 31 (original): The waveguide photodetector of claim 30, wherein the mode converter is comprised of a polysilicon optical structure.

Claim 32 (original): The waveguide photodetector of claim 31, further comprising the fabrication of a polysilicon gate for a transistor at the same time as the fabrication of the polysilicon optical structure.

Claim 33 (original): The waveguide photodetector of claim 30, wherein the mode converter is comprised of a plurality of dielectric structures introduced in substantial proximity to the input to the waveguide photodetector.

Claim 34 (Previously Presented): The waveguide photodetector of any of claims 6, 7, 10, 14, 15, 18, 20, 21, 23 and 32, wherein the transistor is selected from the group comprising: a CMOS transistor, a BiCMOS transistor, a bipolar junction transistor (BJT) and a junction FET (JFET) transistor.

Claim 35 (original): The waveguide photodetector of claim 34, wherein the CMOS transistor is selected from the group of transistors comprising: a fully depleted CMOS transistor, a partially depleted CMOS transistor, a floating body CMOS transistor and a body tied CMOS transistor.

Claim 36 (Withdrawn): A method for communicating signals to a semiconductor device using optical signals comprising:

 sending an optical signal to an input of a germanium on silicon waveguide photodetector located on a semiconductor chip, said germanium on silicon waveguide photodetector comprising:

 a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction stack comprising:

 a silicon layer comprising substantially silicon for conducting light, and

 a germanium layer comprising substantially germanium for conducting light; and

 a cladding comprised of a plurality of dielectric materials;

 an optical input;

 a first plurality of conductive contacts coupled to said germanium layer; and

 a second plurality of conductive contacts coupled to said silicon layer; and,

 outputting an electrical signal through at least one of the second plurality of conductive contacts of the germanium on silicon waveguide photodetector to the input of a semiconductor device located on the semiconductor chip.

Claim 37 (Withdrawn): A method for communicating signals to a semiconductor device using optical signals comprising:

 receiving an optical signal at an input of a germanium on silicon waveguide photodetector located on a semiconductor chip, said germanium on silicon waveguide photodetector comprising:

 a waveguide comprising:

a core comprised of a germanium on silicon heterojunction stack comprising:
a silicon layer comprising substantially silicon for conducting light, and
a germanium layer comprising substantially germanium for conducting light; and
a cladding comprised of a plurality of dielectric materials;
an optical input;
a first plurality of conductive contacts coupled to said germanium layer; and
a second plurality of conductive contacts coupled to said silicon layer; and,
outputting an electrical signal through at least one of the second plurality of conductive contacts of the germanium on silicon waveguide photodetector to the input of a semiconductor device located on the semiconductor chip.

Claim 38 (Currently Amended): A semiconductor chip comprising:

a germanium on silicon waveguide photodetector located on the semiconductor chip, said germanium on silicon waveguide photodetector comprising:
a waveguide comprising:
a core comprised of a germanium on silicon heterojunction stack comprising:
a silicon layer comprising substantially silicon for conducting light, and
a germanium layer comprising substantially germanium for conducting light; and
a cladding comprised of a plurality of dielectric materials;
an optical input;
a first plurality of conductive contacts coupled to said germanium layer; and
a second plurality of conductive contacts coupled to said silicon layer; and,

inputs for receiving optical signals;
outputs for outputting electrical signals; and[,,]
a semiconductor device connected to the germanium on silicon waveguide photodetector outputs
and located on the semiconductor chip, wherein the semiconductor device comprises a CMOS transistor.

Claim 39 (Currently Amended): A computer readable medium comprising a data structure representation of a germanium on silicon waveguide photodetector, the data structure representation comprising:

a data structure representation of a waveguide comprising:
a data structure representation of a core comprised of a germanium on silicon heterojunction stack, the germanium on silicon heterojunction stack comprising :
a silicon layer comprising substantially silicon for conducting light, and
a germanium layer comprising substantially germanium for conducting light; and,
a data structure representation of a cladding comprised of a plurality of dielectric materials; and,
a data structure representation of a first plurality of conductive contacts coupled to the germanium, and
a data structure representation of a second plurality of conductive contacts coupled to the silicon, wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide are formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive contacts is operatively coupled to the CMOS transistor,
wherein the data structure representation is readable by the computer for directing a process for

providing the germanium on silicon waveguide photo detector, the process comprising at least one selected from a group consisting of design simulation, design synthesis, design layout, design verification, and maskwork generation.

Claim 40-41 (Cancelled)

Claim 42 (Currently Amended): A plurality of maskworks comprising a pattern of opaque and transparent areas ~~adapted-to-defin[[e]]~~ing a germanium on silicon waveguide photodetector comprising;

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction, stack comprising :

 a silicon layer comprising substantially silicon for conducting light, and

 a germanium layer comprising substantially germanium for conducting light; and,

 a cladding comprised of a plurality of dielectric materials[[.]],

 a first plurality of conductive contacts coupled to the germanium, and

 a second plurality of conductive contacts coupled to the silicon,
wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide are formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive contacts is operatively coupled to the CMOS transistor.

Claim 43 (original): The maskwork for creating a germanium-on-silicon waveguide photodetector as claimed in claim 42, wherein the maskwork can be used to create an integrated

circuit.

Claim 44 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction, and

 cladding comprised of a plurality of dielectric materials,

 a first plurality of conductive contacts coupled to the germanium and not coupled to the silicon;

 a second plurality of conductive contacts coupled to the silicon and not coupled to the germanium, and wherein said first plurality of conductive contacts are displaced from said second plurality of conductive contacts; and,

 a CMOS transistor body fabricated at the same time as the fabrication of the silicon of the heterojunction.

Claim 45 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction wherein the germanium on silicon heterojunction forms a diode structure with a depletion region, where the diode structure is capable of producing and separating electron hole pairs caused by photons absorbed in the depletion region, and

 a cladding comprised of a plurality of dielectric materials; and,

 a first plurality of conductive contacts coupled to the germanium; and,

 a second plurality of conductive contacts coupled to the silicon,
wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

are formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 46 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction, and

a cladding comprised of:

a bottom cladding;

a side cladding; and,

a top cladding, wherein each of the claddings is comprised of a plurality of
dielectric materials;

a first plurality of conductive contacts coupled to the germanium, and

a second plurality of conductive contacts coupled to the silicon,

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide
are formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 47 (Currently Amended): The waveguide photodetector of claim 46, wherein one of
the plurality of dielectric materials comprising a layer of top cladding is formed from the same
film as a dielectric component of [[a]] the CMOS transistor, where the dielectric component is
selected from a group comprising: an inter-layer dielectric film, a gate spacer, a silicide block, a

dielectric spacer and a passivation film.

Claim 48 (previously presented): The waveguide photodetector of claim 46, wherein the bottom cladding is comprised of the insulating layer of a substrate, where the substrate is selected from the group comprising: silicon on insulator (SOI), silicon on sapphire (SOS) and a silicon membrane (also known as silicon on nothing, SON).

Claim 49 (Currently Amended): The waveguide photodetector of claim 46, further comprising the fabrication of the insulator of a SOI substrate of an integrated circuit at the same time as the fabrication of the bottom cladding of the waveguide, wherein the integrated circuit is selected from the group comprising: a CMOS integrated circuit, a BiCMOS integrated circuit and a bipolar junction integrated circuit.

Claim 50 (Cancelled): The waveguide photodetector of claim 49, wherein the integrated circuit is selected from the group comprising: a CMOS integrated circuit, a BiCMOS integrated circuit and a bipolar junction integrated circuit.

Claim 51 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
a core comprised of a germanium on silicon heterojunction, and
a cladding comprised of a plurality of dielectric materials,
a first plurality of conductive contacts coupled to the germanium, and
a second plurality of conductive contacts coupled to the silicon

wherein each of the second plurality of conductive contacts comprises:

an ohmic contact to the silicon of the heterojunction, and

a conductive plug with a first terminal coupled to the ohmic contact and a second

terminal coupled to a metal layer of a[[n]] CMOS integrated circuit,

wherein at least a portion of a CMOS transistor and the silicon layer of the core of the waveguide

are formed from a starting silicon layer, and

Claim 52 (previously presented): The waveguide photodetector of claim 51, wherein the conductive plug is formed simultaneously with the metal layer.

Claim 53 (previously presented): The waveguide photodetector of claim 51, further comprising the fabrication of an ohmic contact on a terminal region of a transistor at the same time as the fabrication of an ohmic contact on the silicon of the heterojunction, where the terminal region of a transistor is selected from a group comprising: a source, a drain, a gate and a body.

Claim 54 (previously presented): The waveguide photodetector of claim 51, further comprising the fabrication of a conductive plug to an ohmic contact of a transistor at the same time as the fabrication of a conductive plug to an ohmic contact to the silicon of the heterojunction.

Claim 55 (previously presented): The waveguide photodetector of claim 51, wherein an ohmic contact is comprised of a metal silicide.

Claim 56 (previously presented): The waveguide photodetector of claim 51, wherein a conductive plug is comprised of tungsten.

Claim 57 (previously presented): The waveguide photodetector of claim 51, further comprising fabrication of a local interconnection between a pair of transistors, at the same time as fabricating a local interconnection for coupling an ohmic contact on the silicon of the heterojunction with an ohmic contact on a transistor.

Claim 58 (previously presented): The waveguide photodetector of claim 57, wherein the local interconnection is comprised of a material selected from the group comprising: tungsten and aluminum.

Claim 59 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
 a core comprised of a germanium on silicon heterojunction, and
 a cladding comprised of a plurality of dielectric materials,
a first plurality of conductive contacts coupled to the germanium and not coupled to the silicon,
and,
a second plurality of conductive contacts coupled to the silicon and not coupled to the
germanium,
wherein:
 said first plurality of conductive contacts are displaced from said second plurality of

conductive contacts; and,
at least one contact of the pluralities of contacts is coupled to a metal layer on an integrated circuit, where the metal layer has a coupling to a[[n]] CMOS element on the integrated circuit, where at least a portion of the CMOS element and the silicon of the core of the waveguide are formed from a starting silicon layer, and where the element is comprised and selected from the group comprising: a capacitor, a resistor, an inductor, a diode, a transistor and a bond pad.

Claim 60 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
a core comprised of a germanium on silicon heterojunction, and
a cladding comprised of a plurality of dielectric materials,
a first plurality of conductive contacts coupled to the germanium wherein each of the first plurality of conductive contacts comprises:
an ohmic contact to the germanium of the heterojunction, and
a conductive plug with a first terminal coupled to the ohmic contact and a second terminal coupled to a metal layer of a[[n]] COMS integrated circuit, wherein at least a portion of the CMOS integrated circuit and the silicon of the core of the waveguide are formed from a starting silicon layer; and[;]]
a second plurality of conductive contacts coupled to the silicon.

Claim 61 (Currently Amended`): A waveguide photodetector comprising:
a waveguide comprising:

a core comprised of a germanium on silicon heterojunction wherein a plurality of regions in the silicon of the heterojunction comprise a plurality of dopants introduced at the same time as [[the]] an introduction of [[a]] the plurality of dopants into a plurality of regions in the silicon body of a CMOS transistor, wherein the plurality of regions in the silicon body of the CMOS transistor and the silicon of the core of the waveguide are formed from a starting silicon layer, and

a cladding comprised of a plurality of dielectric materials;

a first plurality of conductive contacts coupled to the germanium and not coupled to the silicon; and,

a second plurality of conductive contacts coupled to the silicon and not coupled to the germanium, and wherein said first plurality of conductive contacts are displaced from said second plurality of conductive contacts.

Claim 62 (canceled).

Claim 63 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

a core comprised of a germanium on silicon heterojunction wherein a plurality of regions in the silicon of the heterojunction comprise a first plurality of dopants and a plurality of regions in the germanium of the heterojunction comprise a second plurality of dopants and, wherein the first plurality of dopants is comprised of dopants with electrical charge opposite to the polarity of the dopants comprising the second plurality of dopants; and,

a cladding comprised of a plurality of dielectric materials; and,
a first plurality of conductive contacts coupled to the germanium; and,
a second plurality of conductive contacts coupled to the silicon,
wherein at least a portion of a CMOS transistor and the silicon of the core of the waveguide are
formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 64 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
a core comprised of a germanium on silicon heterojunction wherein a plurality of regions
 in the silicon of the heterojunction comprise a first plurality of dopants and a
 plurality of regions in the germanium of the heterojunction comprise a second
 plurality of dopants and, wherein the first plurality of dopants is comprised of
 dopants with electrical charge equal to the polarity of the dopants comprising the
 second plurality of dopants; and,
a cladding comprised of a plurality of dielectric materials; and,
a first plurality of conductive contacts coupled to the germanium; and,
a second plurality of conductive contacts coupled to the silicon,
wherein at least a portion of a CMOS transistor and the silicon of the core of the waveguide are
formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 65 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

- a core comprised of a germanium on silicon heterojunction, and
- a cladding comprised of a plurality of dielectric materials,

a first plurality of conductive contacts coupled to the germanium;

a second plurality of conductive contacts coupled to the silicon;

an input to the waveguide photodetector;

a silicon waveguide with an input and an output; and,

a mode converter with an input and an output, where the output of the mode converter is coupled to the input of the waveguide photodetector, and where the input to the mode converter is coupled to the output of the silicon waveguide,

wherein at least a portion of a CMOS transistor and the silicon of the core of the waveguide are formed from a starting silicon layer, and

wherein at least one conductive contact of the first and the second pluralities of conductive contacts is operatively coupled to the CMOS transistor.

Claim 66 (previously presented): The waveguide photodetector of claim 65, wherein the mode converter is comprised of a polysilicon optical structure.

Claim 67 (previously presented): The waveguide photodetector of claim 66, further comprising the fabrication of a polysilicon gate for a transistor at the same time as the fabrication of the polysilicon optical structure.

Claim 68 (previously presented): The waveguide photodetector of claim 65, wherein the mode converter is comprised of a plurality of dielectric structures introduced in substantial proximity to the input to the waveguide photodetector.

Claim 69 (previously presented): The waveguide photodetector of any of claims 6, 44, 47, 50, 53, 54, 57, 59, 60, 61 and 67, wherein the transistor is selected from the group comprising: a CMOS transistor, a fully depleted CMOS transistor, a partially depleted CMOS transistor, a floating body CMOS transistor and a body tied CMOS transistor.

Claim 70 (Currently Amended): A computer readable medium comprising a data structure representation of a germanium on silicon waveguide photodetector, the germanium on silicon waveguide photodetector comprising:

a data structure representation of a waveguide comprising:
a data structure representation of a core comprised of a germanium on silicon heterojunction, and
a data structure representation of a cladding comprised of a plurality of dielectric materials.

a data structure representation of a first plurality of conductive contacts coupled to the germanium, and

a data structure representation of a second plurality of conductive contacts coupled to the silicon

wherein the data structure representation of [[a]]the germanium on silicon waveguide photodetector is selected from a list consisting of a component in a software library having a fixed specification for an integrated circuit netlist, a netlist, a CAD (computer-aided design)

representation, and a hardware definition language representation,
wherein at least a portion of a CMOS transistor and the silicon of the core of the waveguide are
formed from a starting silicon layer, and
wherein at least one conductive contact of the first and the second pluralities of conductive
contacts is operatively coupled to the CMOS transistor.

Claim 71 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
 a core comprised of a germanium on silicon heterojunction, and
 cladding comprised of a plurality of dielectric materials,
 a first plurality of electrical contacts coupled to the germanium;
 a second plurality of electrical contacts coupled to the silicon; and,
 a CMOS transistor body fabricated at the same time as the fabrication of the silicon of the
 heterojunction, wherein the CMOS transistor body and the silicon of the core of the
waveguide are formed from a starting silicon layer and wherein the CMOS transistor
 body is external to the waveguide and displaced from the waveguide.

Claim 72 (Currently Amended): A waveguide photodetector comprising:
a waveguide comprising:
 a core comprised of a germanium on silicon heterojunction, and
 a cladding comprised of a plurality of dielectric materials,
 a first plurality of conductive contacts coupled to the germanium, and
 a second plurality of conductive contacts coupled to the silicon wherein at least one contact of

the pluralities of contacts is electrically coupled to a metal layer on an integrated circuit, where the metal layer has an electrical coupling to an CMOS electronic element on the integrated circuit, where at least a portion of the CMOS electronic element and the silicon of the core of the waveguide are formed from a starting silicon layer, and where the electronic element is external to the waveguide and displaced from the waveguide, and wherein the electronic element is selected from the group comprising: a capacitor, a resistor, an inductor, a diode, a transistor and a bond pad.

Claim 73 (Currently Amended): A waveguide photodetector comprising:

a waveguide comprising:

 a core comprised of a germanium on silicon heterojunction wherein a plurality of regions in the silicon of the heterojunction comprise a plurality of dopants introduced at the same time as [[the]] an introduction of [[a]] the plurality of dopants into a plurality of regions in the silicon body of a CMOS transistor body, wherein the CMOS transistor body and the silicon of the core of the waveguide are form from a starting silicon layer, and wherein the CMOS transistor is external to the waveguide and displaced from the waveguide, and

 a cladding comprised of a plurality of dielectric materials;

 a first plurality of electrical contacts coupled to the germanium; and,

 a second plurality of electrical contacts coupled to the silicon.